

**Dialog DataStar**

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## Advanced Search: INSPEC - 1969 to date (INZZ)

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Search history:

No.	Database	Search term	Info added since	Results	
1	INZZ	birefringence AND (rotating OR clocking)	unrestricted	245	<a href="#">show titles</a> <i>bb</i>
2	INZZ	(lithograph\$6 OR microlithograph\$6 OR photolithograph\$6) AND (rotating OR clocking)	unrestricted	135	<a href="#">show titles</a> <i>bb</i>
3	INZZ	(crystal\$4 OR birefringen\$2) NEAR lens\$2 AND (rotating OR clocking)	unrestricted	10	<a href="#">show titles</a> <i>bb</i>
4	INZZ	(intrinsic\$4 OR inherent\$2) NEAR birefringen\$2	unrestricted	243	<a href="#">show titles</a> <i>bb</i>

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- ☐ Classification codes A: Physics, 7
- ☐ Classification codes A: Physics, 8
- ☐ Classification codes A: Physics, 9
- ☐ Classification codes B: Electrical & Electronics, 0-5
- ☐ Classification codes B: Electrical & Electronics, 6-9
- ☐ Classification codes C: Computer & Control
- ☐ Classification codes D: Information Technology
- ☐ Classification codes E: Manufacturing & Production
- ☐ Treatment codes

	Type	L #	Hits	Search Text	DBs
7	BRS	L7	308 78	(355/53 or 355/67 or 355/71).ccls. and (birefringen\$2 (doubl\$1 adj refract\$3) or retard\$6 or ((polariz\$6 polaris\$6) with (rotat\$3 (phase with shift\$3))))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
9	BRS	L9	839	(birefringen\$2 (doubl\$1 adj refract\$3) birefract\$3 retard\$6 ((polaris\$6 polariz\$5) with (rotat\$3 (phases with shift\$3)))) with (((intrinsic\$4 adj birefringen\$2) (intrinsic\$4 adj birefract\$3) (intrinsic\$4 adj doubl\$1 adj refract\$3) (cubic adj crystal\$4) (exposure adj apparatus) (exposing adj substrate) photolithographic\$4 lithographic\$4 microlithographic\$4 (wafer adj stepper\$1)))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB
10	BRS	L10	804 88	9 not 7	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB